

GaAsSb/AlGaAsP Superlattice Polarized Electron Source

Contract # DE-SC0009516

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DoE SBIR/STTR Exchange Meeting

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SVT Associates, Inc.

SVT Associates Company Overview

Founded in 1993 as Molecular Beam Epitaxy (MBE) equipment provider

- Originated from Perkin Elmer Physical Electronics MBE Group
- One of today's leading MBE suppliers by continual product development
- Over 160 MBE systems now in the field
- Strong UHV hardware, epitaxial growth, and thin film expertise
- Technology Driven Company
 - >30% employees are PhD scientists (currently 30 employees total)
 - Key engineers > 25 years experience in MBE and UHV technology
- Diverse system product line spanning Molecular Beam Epitaxy (MBE), Thin Film Deposition (i.e. ALD, PVD, PLD and Solar), and In-situ Thin Film Monitoring
- Only MBE Company with System, Components, Process, In-situ Monitoring Expertise with our own Applications Laboratory and Characterization Facility



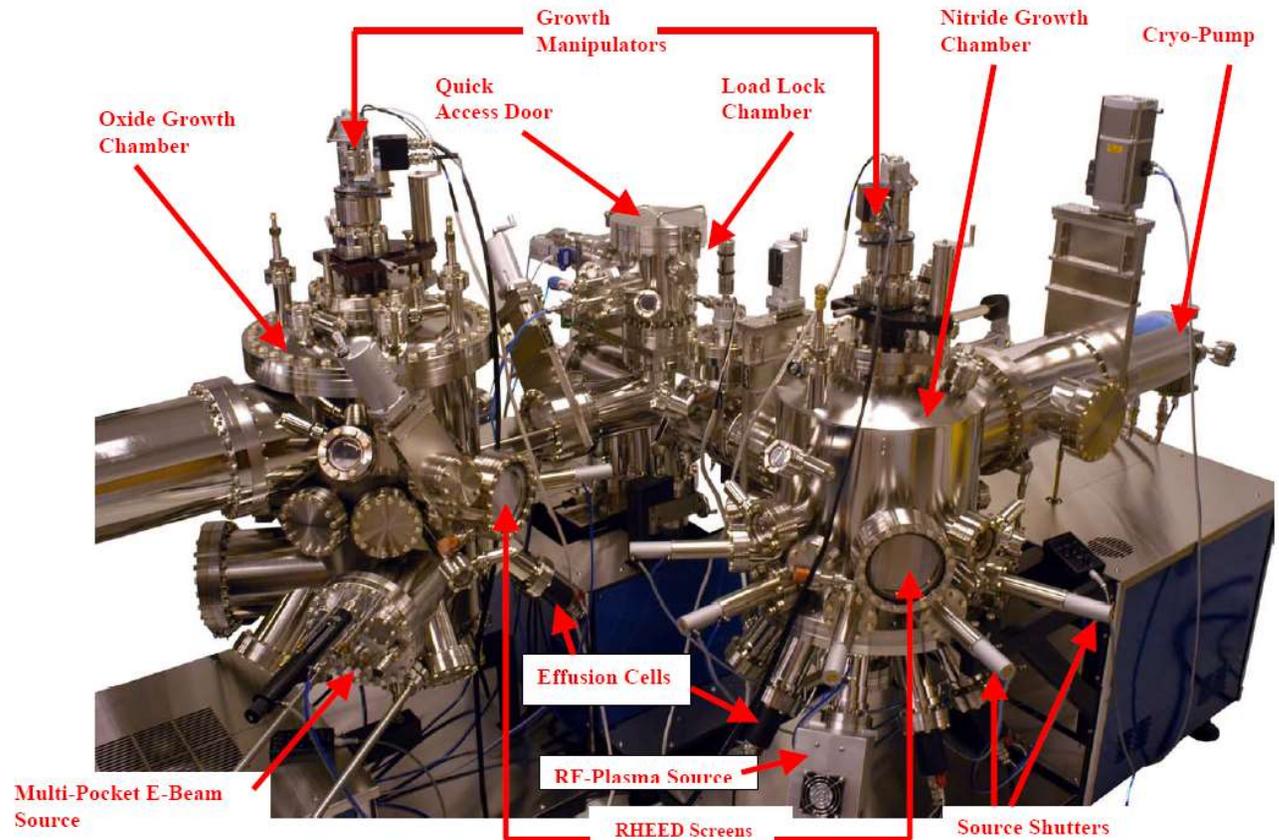
SVT Facilities and Capabilities

- Material deposition systems: MBE
PLD, ALD, PECVD, ICP

Established know-how:
8 Applications Laboratory MBE
systems producing world class
epitaxial growth, feeding
requirements back to equipment
designers

•Complete semiconductor
material characterization facility:
HR-XRD, FTIR, Hall, Low-temp
probe station, Semiconductor
parameter analyzer,
ellipsometer.

•Device Fabrication
Class-100 clean room



Dual Oxide - Nitride MBE



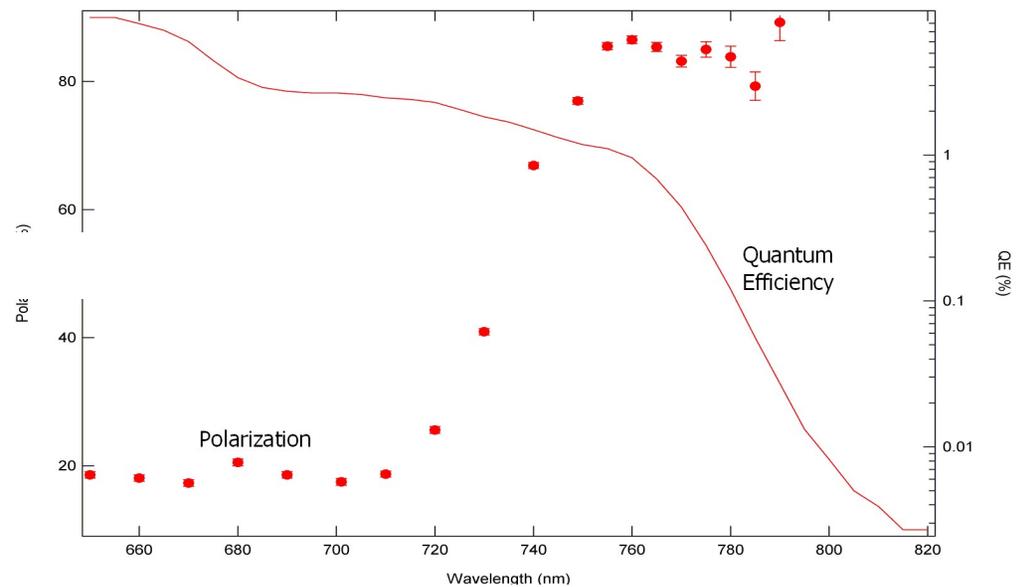
Semiconductors Research at SVT

- US government, industrial research grants, and internal programs
- Established research collaboration with many universities: Illinois, North Carolina State, Florida, Stanford ...
- Highly technically oriented, PhD scientists & engineers
- > 100 book chapters, publications and presentations
- Significant Antimonide, Nitride and ZnO accomplishments
 - High power HEMT & MOSHEMT
 - Commercialized solar blind UV detector products
 - High efficiency photocathode
 - Innovative LED utilizing Quantum Structures
 - New mid Infrared Laser and Photodiode
 - Rainbow colored MgZnCdO



Polarized Photocathode

- More than 10 year R&D on polarized photocathode
- Dedicated MBE system for material growth of polarized photocathode. equipped with As, P, crackers
- Over 90% polarization with 1% QE achieved by previous SBIR programs and collaborations with DoE labs (JLab, SLAC, and BNL)



Program Overview

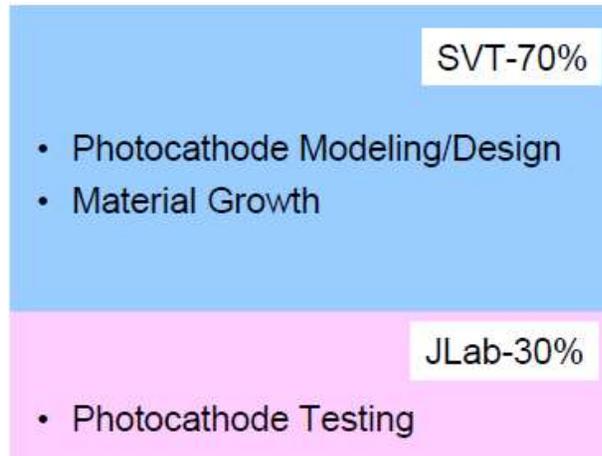
Program title: GaAsSb/AlGaAsP Superlattice High-Polarization Electron Source

Ultimate goal:

cw polarized electron sources
with >85% polarization and >10
mA beam current

Present Applications:

- DoE needs: high energy accelerators
- Spintronics



Potential Applications:

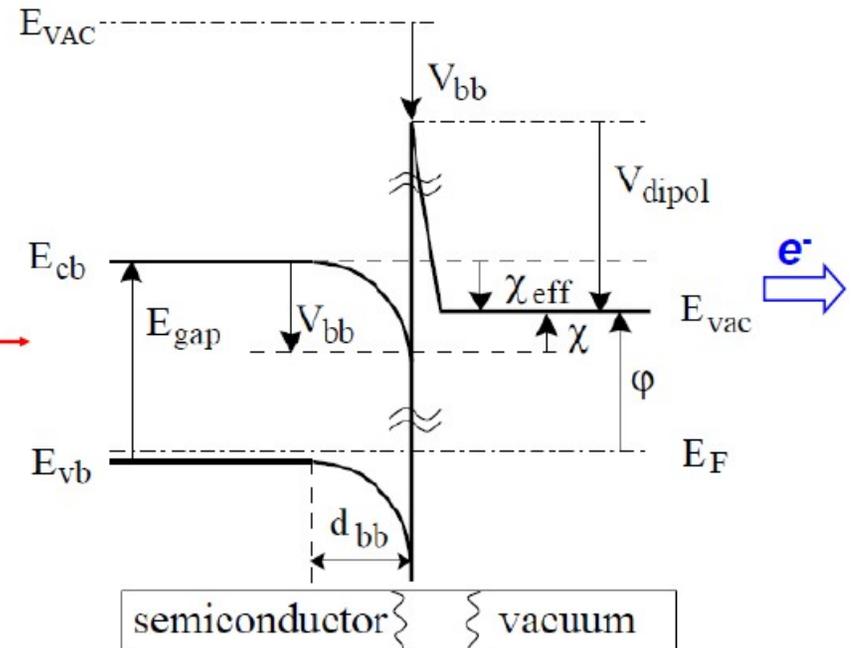
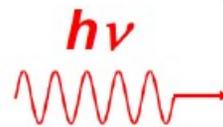
- Surface analysis
- Quantum computing
- Magnetic imaging

Photocathode - General Properties

Photons → free electrons in vacuum

1. Optical absorption
2. Electron transport to surface
3. Escape from surface to vacuum (NEA)

Two aspects of emitted electrons in polarized photocathode: density and spins



- Improvement:
1. increase QE
 2. increase polarization

Why Sb-based SL?

Existing structures in literature

1. InGaAs/AlGaAs (strained well), 70-80%, QE~0.7%
2. GaAs/GaAsP (strained well), 92%, measured, QE~1%
3. GaAs/AlInGaAs (strained barrier), 91%
4. AlInGaAs/GaAsP (strain-balanced), 84%
5. AlInGaAs/AlGaAs (strained well), 92% with QE~0.85%

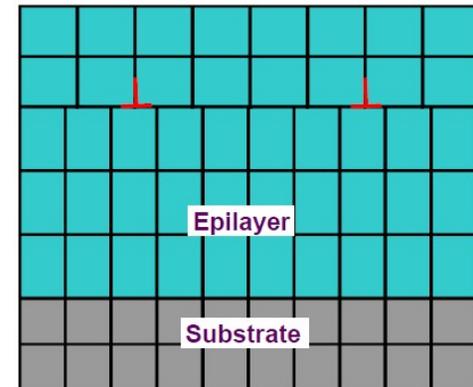
All HH-LH splittings < 95 meV

GaAs/GaAs_{0.64}P_{0.36} SL:

Best overall performance thus far, HH-LH splitting $\delta \sim 92$ meV

GaAs_{0.85}Sb_{0.15}/Al_{0.25}GaAsP_{0.15} SL:

- highest VB offset \Rightarrow Highest HH-LH splitting: $\delta > 150$ meV resulting in highest initial polarization
- Dislocation-free SL material since no strain relaxed layer required, boost QE
- No need to grow very thick metamorphic buffer (5-10 μm), cost-effective



GaAsSb/AlGaAsP SL Photocathode – High Polarization and High QE



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Cooled shutter for As/P/Sb material system

- As and P very volatile -> unwanted P into GaAsSb
- Instant flux shut off of P by cooled shutter -> sharp SL interfaces

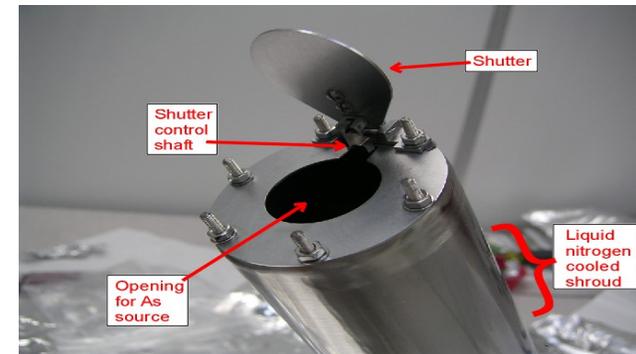
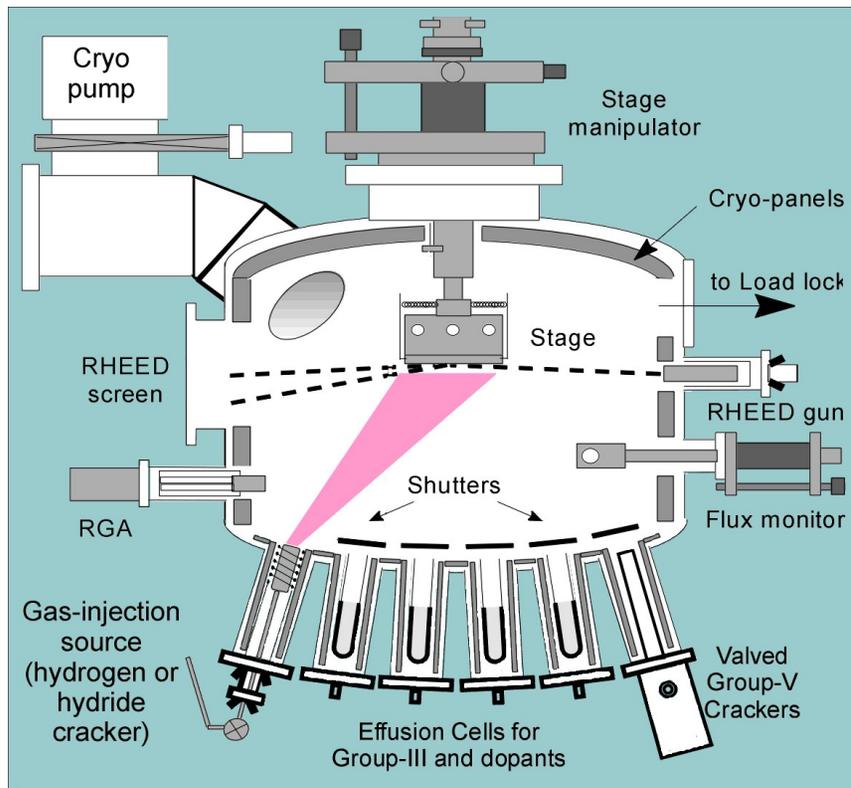
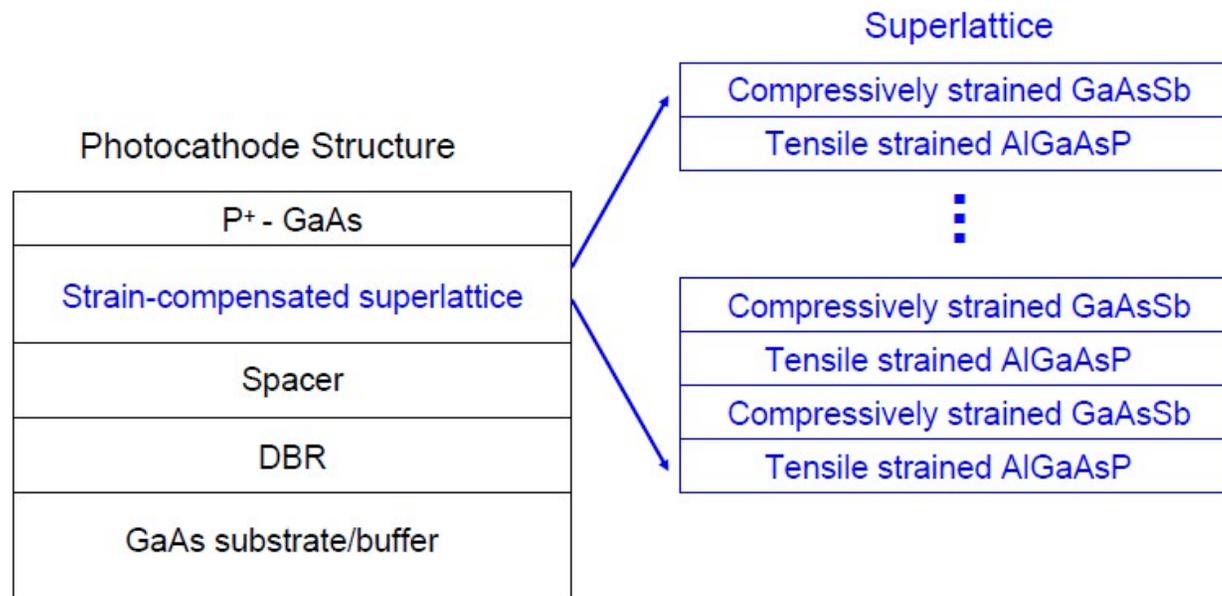


Photo of the output end of the independently cooled shroud/shutter assembly for phosphorus flux abatement. The shutter can change states in a sub-second time scale.

Key benefits of proposed approaches

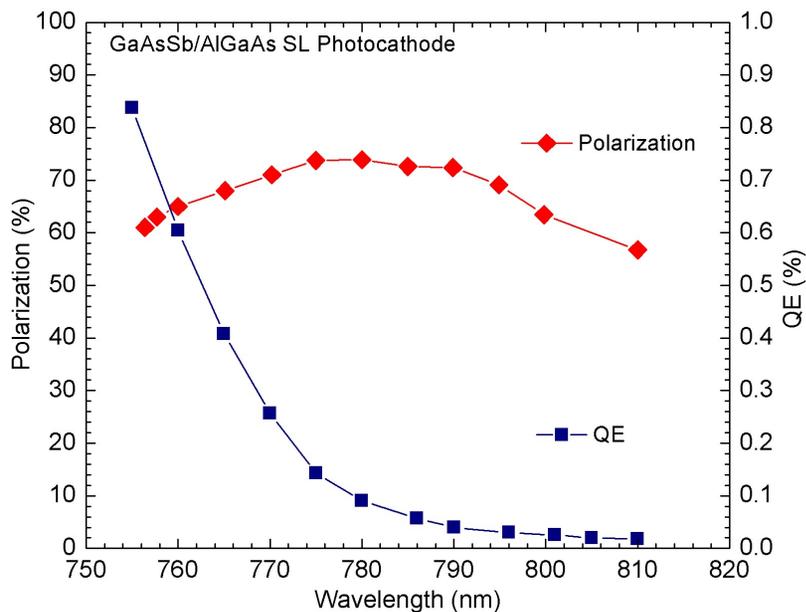
- Improved polarization by large HH-LH splitting.
- Significantly improved material quality and thicker SL absorber region boosting QE by fully strain-compensated GaAsSb/AlGaAsP SL.
- An effective GaAs(P)/AlAs(P) DBR structure to enhance QE through more efficient photon absorption.
- Cooled shutter approach to improve interface quality of GaAsSb/AlGaAsP SLs.



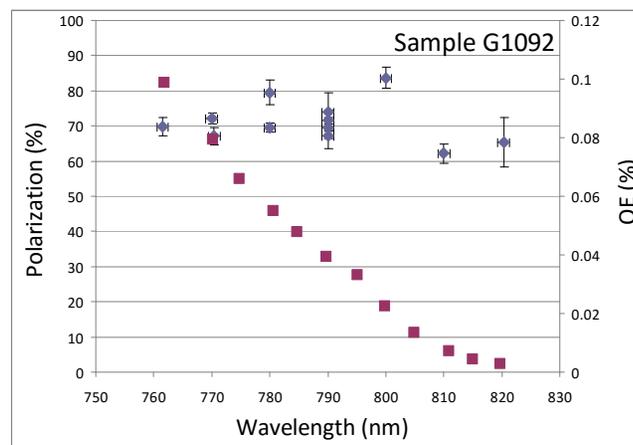
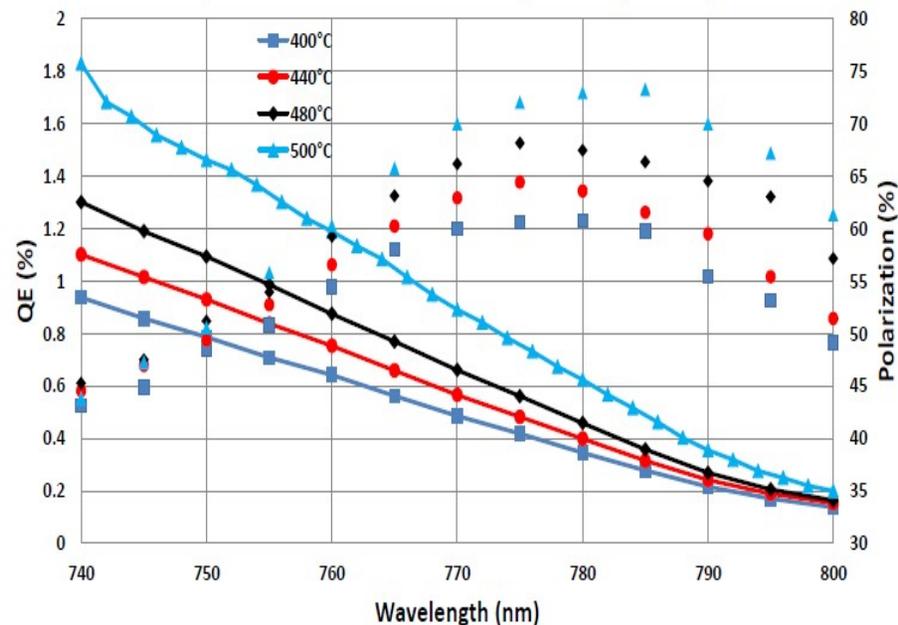
Polarization of Sb-based SL photocathodes

Best polarization for Sb-SL: 84%

Our goal: >92%



QE and Polarization for GaAsSb/AlGaAs (#75304)



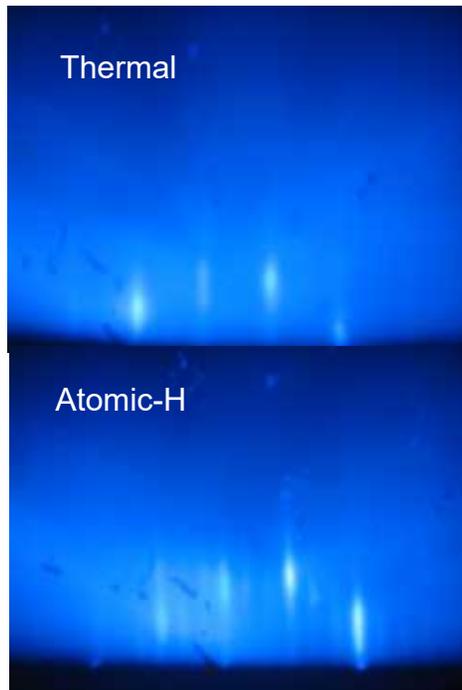
Polarization of Sb-based SL photocathodes

Thermal native oxide removal test under RHEED monitor performed

- 520C required to fully remove surface oxide even with As capping, SL growth temperature – 490C
- Structural damage of Sb-based SL due to heating

Nest step – two approaches

- Atomic hydrogen, native oxide on GaAs can be removed by atomic-H below 450C
- Other surface capping material : Sb



Oxide removal test - RHEED

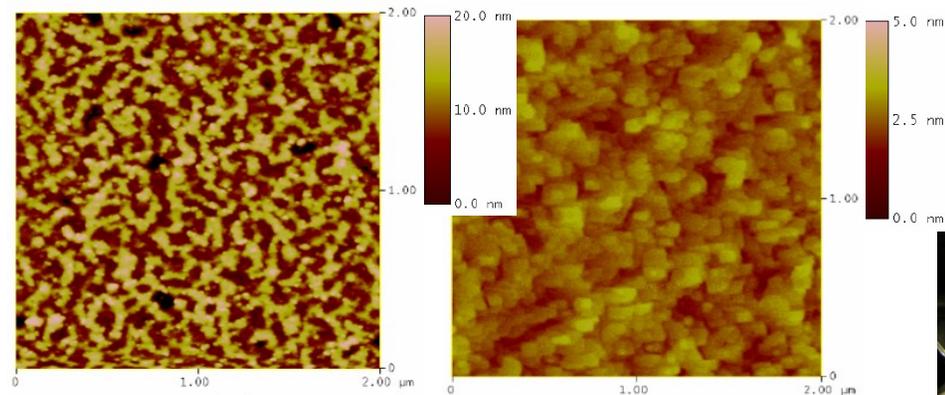
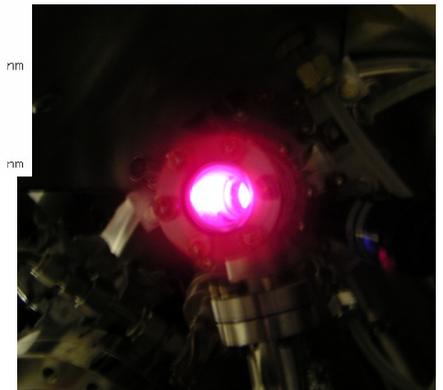


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Img. Rms (Rq)	4.669 nm
Img. Ra	3.851 nm
Img. Srf. area	4.252 μm^2
Img. Prj. Srf. area	4.000 μm^2
Img. Srf. area diff	5.295 %
Img. SAE	1.027

Image Statistics	
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Img. Rms (Rq)	0.374 nm
Img. Ra	0.296 nm
Img. Srf. area	4.003 μm^2
Img. Prj. Srf. area	4.000 μm^2
Img. Srf. area diff	0.063 %
Img. SAE	1.000



Atomic-H generated from an SVT RF-source

As: porous
Sb: better surface coverage



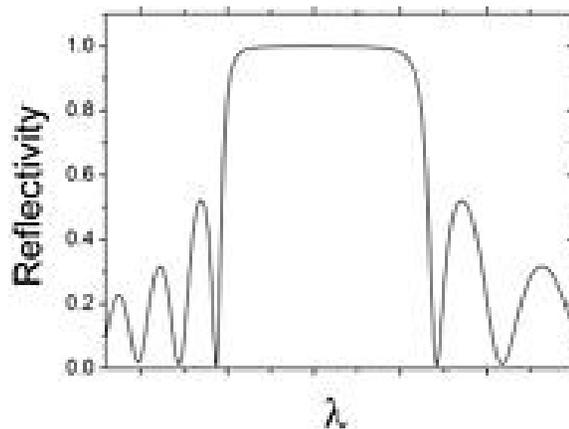
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Distributed Bragg Reflector (DBR)

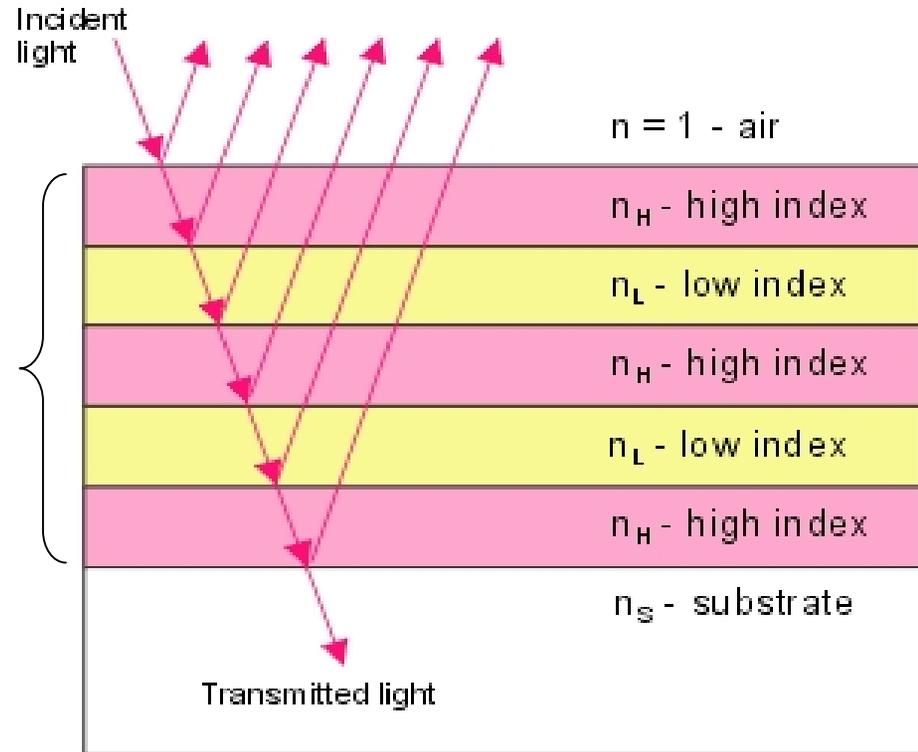
- Core SL layer very thin (~100-200nm) due to short spin relaxation time –very low absorption (a few percent) and hence low QE
- Perfect reflector
- Reflection ~99% for 20-period GaAs(P)/AlAs(P) DBR

DBR requirement:

- Abrupt interfaces
- Good periodicity



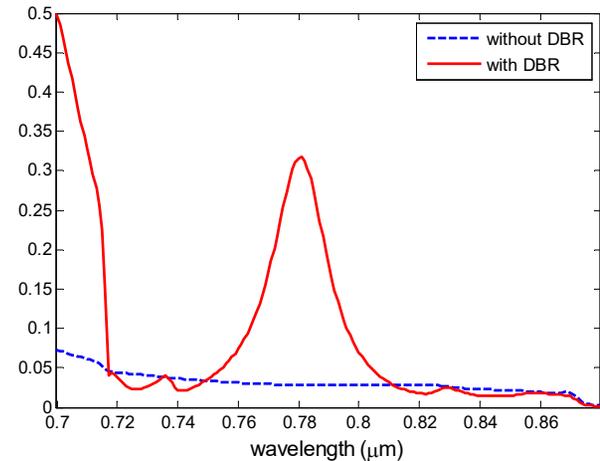
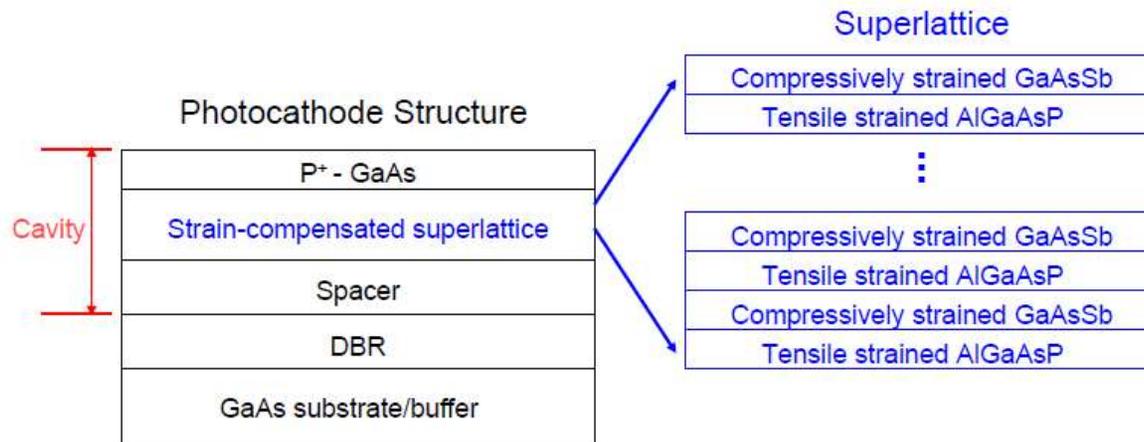
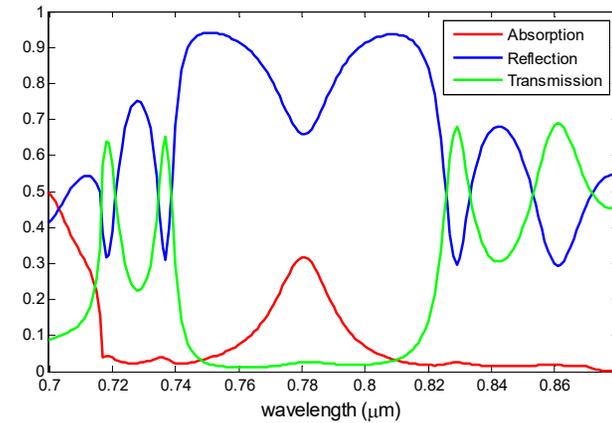
DBR stacks



DBR with Fabry-Perot Cavity

- Fabry-Perot cavity formed between wafer/air interface and DBR/spacer interface
- Resonant light absorption in SL core layers due to F-P cavity
- Absorption resonant peaks very sensitive to cavity length – accurate layer thickness and composition control required

Calculated absorption of the superlattice with DBR and Fabry-Perot cavity (right). (8-pair DBRs)



Calculated absorption spectra for 12-pair DBR and w/o DBR

No QE Enhancement for Poor DBR

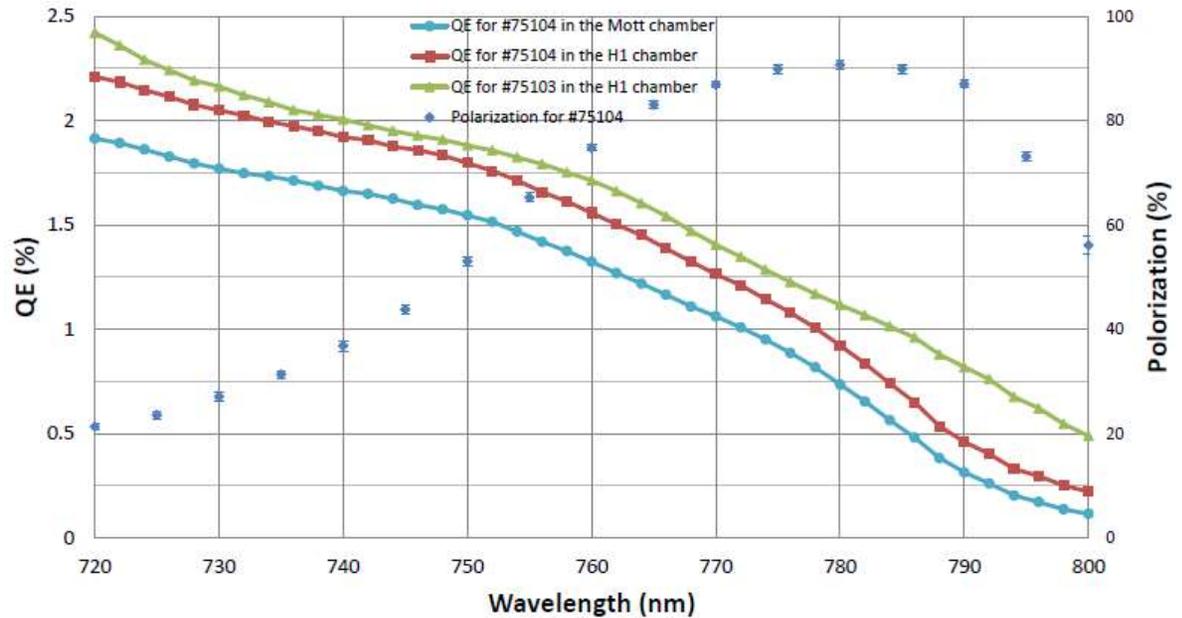
GaAsP/AIAsP DBR

- High growth temperature favorable to single-layer GaAsP and AIAsP
- For GaAsP/AIAsP multi-layer structure, high growth temperatures cause interface damage



Forbidden window for growth of AIAs(P) : 620-680 C

QE and Polarization for the nonDBR (#75103) & DBR (#75104) cathode

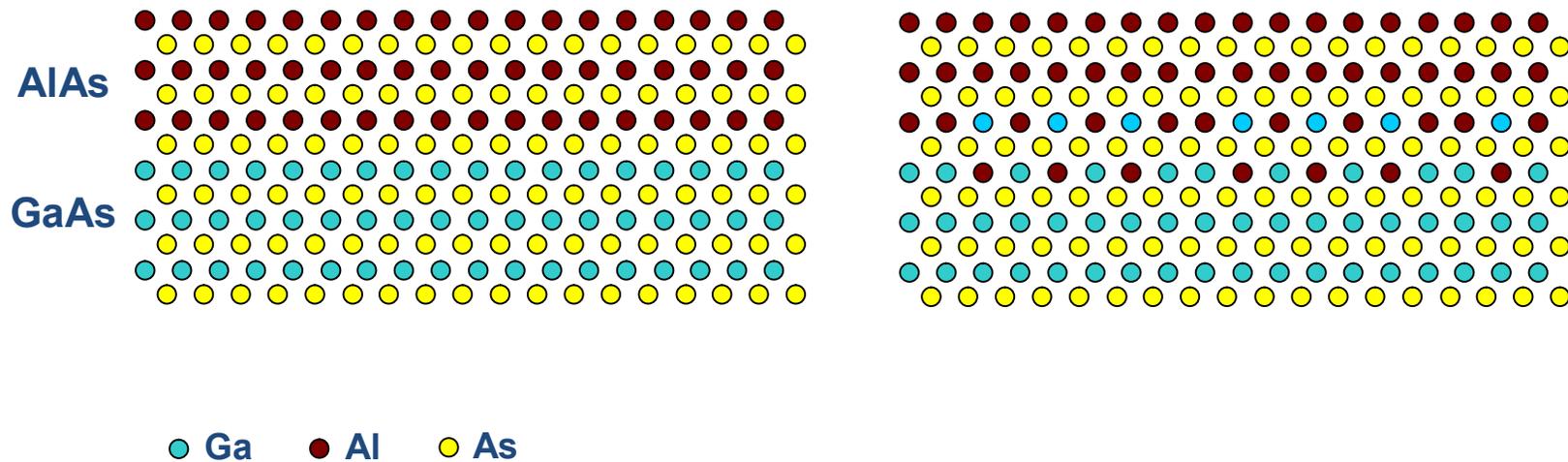


Growth temperature: 680 C

Structural Damage due to Ga Diffusion at High Temperatures

Ga atoms diffused at the interfaces

- Poor interface quality
- loss of periodicity of DBR



New Quantum Efficiency Milestone Achieved!

- Low growth temperature
- Very low growth rate for Al-containing layers

**Important milestone:
Over 5% QE with 87% polarization for the first
time!**

Next goal: >10% QE

Preliminary results promising; still room to improve.

- Lack of data for optical parameters of AlAsP
- Best growth window for GaAs(P)/AlAs(P) unknown



Summary

- SL structure design and DBR design completed
- High quality GaAsP/AlAsP DBR material achieved
- MBE growth of GaAsSb/(Al)GaAsP SL
- Surface oxide removal test performed to investigate the cause of low polarization of Sb-based SL photocathodes
- **Over 5% QE with 87% polarization achieved— New world record**
- Substrate heater upgrade – temperature variation over 3-inch $< 5\text{ }^{\circ}\text{C}$
- New surface capping material; Atomic-H assisted surface oxide removal